

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2871
Hyperion Sec
Division
516102

In re Application of:

PATENT APPLICATION

Inventors: Apostolos Voutsas

Attorney Docket No.
SLA0592

Serial No: 09/893,866

Group Art Unit: 2871

Filed: June 28, 2001

Examiner:

Title: METHOD FOR FORMING
SILICON FILMS WITH TRACE
IMPURITIES

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited in the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Hon. Commissioner for Patents, Washington, D.C. 20231 on

David C. Ripma, 27,672
Signature Date: 2/25/02

TRANSMITTAL OF SUPPLEMENTAL
DECLARATION UNDER 37 C.F.R. §1.67(a)

Hon. Commissioner for Patents
Washington, D.C. 20231

Sir:

This correspondence transmits an accompanying Supplemental Declaration in the above-identified patent application. The Supplemental Declaration includes language inadvertently omitted from the originally-filed Declaration stating that the person making the declaration has reviewed and understands the contents of the specification, including the claims, as amended by

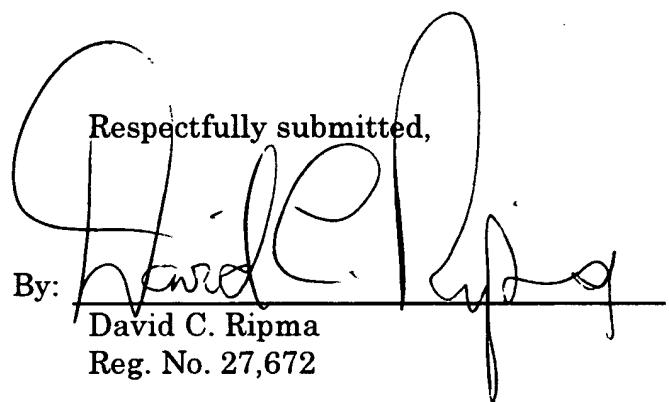
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any amendment specifically referred to in the declaration, and acknowledges the duty to disclose information which is material to the examination of the application in accordance with 37 C.F.R. §1.56.

Please enter this Supplemental Declaration in the application file.

The Commissioner is hereby authorized to charge any fees associated with this communication to Deposit Account No. 19-1457. A duplicate copy of this authorization is enclosed.

Date: Feb 25, 2002

Respectfully submitted,
By: 
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